



PATENT

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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Christa M. Caliva

Applicant : Konstantin Holdermann  
Application No. : 10/090,915  
Filed : March 5, 2002  
Title : ETCHING SOLUTION FOR WET CHEMICAL  
PYRAMIDAL TEXTURE ETCHING OF SILICON  
SURFACES  
Grp./Div. : 1746  
Examiner : To Be Assigned  
Docket No. : 47585/MJM/S969

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INFORMATION DISCLOSURE STATEMENT  
FOR A CONTINUING NON-CPA APPLICATION

Assistant Commissioner for Patents  
Washington, D.C. 20231

Post Office Box 7068  
Pasadena, CA 91109-7068  
March 7, 2003

Commissioner:

In compliance with the duty of disclosure under 37 CFR §§ 1.56, 1.97 and 1.98, enclosed is FORM PTO/SB/08A/B.

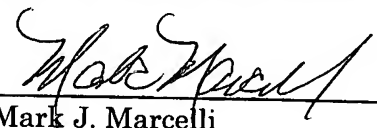
The reference listed thereon, is not enclosed because it was of record in the parent application, Application No. 09/272,022, filed March 5, 2002, and issued as Patent No. 6,451,218 on September 17, 2002.

It is respectfully requested that this reference be considered in the examination of this application, and identified in the list of references cited on the patent issuing on this application.

Respectfully submitted,

CHRISTIE, PARKER & HALE, LLP

By

  
Mark J. Marcelli  
Reg. No. 36,593  
626/795-9900

CM/cmc

Enclosure: Form PTO/SB/08A/B  
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